

L Number	Hits	Search Text	DB	Time stamp
1	38	((ozone near15 generator) or ozone) near15 (gas or atmosphere)) same (wafer or semiconductor or substrate) same (spray or sprayer or nozzle or jet) same (spin or spinning or rotor or rotate or rotary or turn or rotating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 06:04
2	3	((ozone near15 generator) or ozone) near15 (gas or atmosphere)) same (wafer or semiconductor or substrate) same (spray or sprayer or nozzle or jet) same (spin or spinning or rotor or rotate or rotary or turn or rotating)	USOCR	2004/04/21 06:04
3	6	((ozone near15 generator) or ozone) near15 (gas or atmosphere)) and (wafer or semiconductor or substrate) same (spray or sprayer or nozzle or jet) and (spin or spinning or rotor or rotate or rotary or turn or rotating)	USOCR	2004/04/21 06:05
4	627	((ozone near15 generator) or ozone) near15 (gas or atmosphere)) and (wafer or semiconductor or substrate) same (spray or sprayer or nozzle or jet) and (spin or spinning or rotor or rotate or rotary or turn or rotating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 06:46
5	26851	(ozone near15 generator) or (ozone near15 (gas or atmosphere))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 06:50
6	9221	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) and (wafer or semiconductor or substrate) and (spray or sprayer or nozzle or jet) and (spin or spinning or rotor or rotate or rotary or turn or rotating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 06:51
7	8938	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) and (wafer or semiconductor or substrate) and (spray or sprayer or nozzle or jet) and (spin or spinning or rotor or rotate or rotary or turn or rotating) and (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 06:56
8	349	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) and (wafer or semiconductor or substrate) and (spray or sprayer or nozzle or jet) and (spin or spinning or rotor or rotate or rotary or turn or rotating) and (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating)	USOCR	2004/04/21 06:57
9	8550	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) and ((wafer or semiconductor or substrate) near15 (spin or spinning or rotor or rotate or rotary or turn or rotating)) and (spray or sprayer or nozzle or jet) and (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 06:58

10	8425	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) and ((wafer or semiconductor or substrate) near15 (spin or spinning or rotor or rotate or rotary or turn or rotating)) and ((spray or sprayer or nozzle or jet) near15 (water or liquid or chemical or acid or solution or solvent)) and (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:00
11	8425	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) and ((wafer or semiconductor or substrate) near15 (spin or spinning or rotor or rotate or rotary or turn or rotating)) and ((spray or sprayer or nozzle or jet) near15 (water or liquid or chemical or acid or solution or solvent)) and (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:00
12	8331	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) and ((wafer or semiconductor or substrate) near15 (spin or spinning or rotor or rotate or rotary or turn or rotating)) and (((spray or sprayer or nozzle or jet) near15 (water or liquid or chemical or acid or solution or solvent)) near25 (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:01
13	8249	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) same ((wafer or semiconductor or substrate) near15 (spin or spinning or rotor or rotate or rotary or turn or rotating)) and (((spray or sprayer or nozzle or jet) near15 (water or liquid or chemical or acid or solution or solvent)) near25 (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:01
14	8244	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) same ((wafer or semiconductor or substrate) near15 (spin or spinning or rotor or rotate or rotary or turn or rotating)) same (((spray or sprayer or nozzle or jet) near15 (water or liquid or chemical or acid or solution or solvent)) near25 (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:01
15	8239	(ozone near15 generator) or (ozone near15 (gas or atmosphere))near55 ((wafer or semiconductor or substrate) near15 (spin or spinning or rotor or rotate or rotary or turn or rotating)) same (((spray or sprayer or nozzle or jet) near15 (water or liquid or chemical or acid or solution or solvent)) near25 (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:02

16	8238	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) near55 ((wafer or semiconductor or substrate) near15 (spin or spinning or rotor or rotate or rotary or turn or rotating)) near55 (((spray or sprayer or nozzle or jet) near15 (water or liquid or chemical or acid or solution or solvent)) near25 (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:08
17	8237	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) near55 ((wafer or semiconductor or substrate) near15 (spin or spinning or rotor or rotate or rotary or turn or rotating)) near55 (((spray or sprayer or nozzle or jet) near15 (water or liquid or chemical or acid or solution or solvent)) near25 (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating)) and 134/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:10
18	22540	(ozone near10 generator) or (ozone near10 (gas or atmospphere))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:11
19	26080	(ozone near10 generator) or (ozone near10 (gas or atmosphere))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:11
20	21812	(wafer or semiconductor or substrate) same (ozone near10 generator) or (ozone near10 (gas or atmosphere))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:12
21	11644	(ozone near10 generator) or (ozone near10 (gas or atmosphere)) same ((wafer or semiconductor or substrate) nrat20 (spin or spinning or rotor or rotate or rotary or turn or turning or rotating))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:13
22	8251	(ozone near10 generator) or (ozone near10 (gas or atmosphere)) same ((wafer or semiconductor or substrate) near20 (spin or spinning or rotor or rotate or rotary or turn or turning or rotating))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:14
23	8169	(ozone near10 generator) or (ozone near10 (gas or atmosphere)) same ((wafer or semiconductor or substrate) near20 (spin or spinning or rotor or rotate or rotary or turn or turning or rotating)) same (sprayer or spray or spraying or jet or nozzle) near15 ((water or chemical or liquid or chemicals or acid or solvent)) ((ozone near10 generator) or (ozone near10 (gas or atmosphere)) same ((wafer or semiconductor or substrate) near20 (spin or spinning or rotor or rotate or rotary or turn or turning or rotating)) same (sprayer or spray or spraying or jet or nozzle) near15 ((water or chemical or liquid or chemicals or acid or solvent))) and 134/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:16
24	219		USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:16

25	2579	((ozone near10 generator) or (ozone near10 (gas or atmosphere)) same ((wafer or semiconductor or substrate) near20 (spin or spinning or rotor or rotate or rotary or turn or turning or rotating)) same (sprayer or spray or spraying or jet or nozzle) near15 ((water or chemical or liquid or chemicals or acid or solvent))) and (134/\$.ccls. or wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontaminating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 07:17
-	3	"6235112" and (heat or heater or hot or heated or heating)	USPAT	2004/04/20 07:18
-	1	"6551409" and (heat or heater or hot or heated or heating)	USPAT	2004/04/20 08:07
-	4	"6325081" and ((heat or heater or hot or heated or heating) or (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate) or ozone)	USPAT	2004/04/20 08:10
-	4	"6325081" and ((heat or heater or hot or heated or heating) or (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone)	USPAT	2004/04/20 08:48
-	1	"6684890"	USPAT	2004/04/20 08:17
-	689	134/\$.ccls. and (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) same (wafer or semiconductor)	USPAT	2004/04/20 08:19
-	22	"5378317" and ((heat or heater or hot or heated or heating) or (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone)	USPAT	2004/04/20 08:51
-	1	"5990060" and ((heat or heater or hot or heated or heating) or (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone)	USPAT	2004/04/20 08:58
-	18868	((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual)) and ((heat or heater or hot or heated or heating) or (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/20 09:01
-	547	((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual)) and ((heat or heater or hot or heated or heating) or (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone) and 134/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/20 09:06
-	371	((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual)) and ((sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone) and 134/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/20 10:53

		0	((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual)) and ((sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone) and 134/\$.ccls.	IBM_TDB	2004/04/20 10:21
		1	((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual)) and ((sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone) and 134/\$.ccls.	USOCR	2004/04/20 10:26
		1	((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual)) and ((sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) and (washing or cleaning or clean or decontaminate or rinse or rinsing) 134/\$.ccls.	USOCR	2004/04/20 10:27
	302		((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual)) and ((sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate)) and (washing or cleaning or clean or decontaminate or rinse or rinsing) 134/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/20 10:27
	3068		((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual)) and ((sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate)) and (washing or cleaning or clean or decontaminate or rinse or rinsing or decontaminating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/20 10:27
	132		((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual)) and ((sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone) and 134/\$.ccls. and( (raised or raising) and (lowered or lowering))	USPAT; US-PGPUB	2004/04/20 11:18
	2		((wafer or semiconductor or substrate) near25 (spin or spinning or turn or turning or rotate or rotating or rotor)) same (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) and 134/\$.ccls.	USOCR	2004/04/20 11:22
	308		((wafer or semiconductor or substrate) near25 (spin or spinning or turn or turning or rotate or rotating or rotor)) same (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) and 134/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 06:00